



PiezoMEMS 2024, Day 1 - March 19th

Time	Topic	Company / Organisation	Speaker
08:00 – 08:15	Opening Remarks		Stephan Tiedke, Susan Trolier-McKinstry
08:15 – 10:10	Thin film Growth-PZT		
08:15 – 08:40	Electrocaloric cooling and nonlinear pyroelectric energy harvesting	LIST	Emmanuel Defay
08:40 – 09:05	Maturing and Emerging PiezoMEMS Technologies at the DEVCOM Army Research Laboratory	ARL	Nicolas Strnad
09:05 – 09:30	Piezoelectric PZT-based MEMS loudspeaker for in-ear applications	Fraunhofer ISIT	Fabian Stoppel
09:30 – 09:55	Advanced quality control for Sputtered PZT MEMS	Silex	Niklas Svedin
09:55 – 10:10	Large area PLD PZT thin films for fast growing piezoelectric thin film demand for internet	Piemacs	Sarunas Bagdzevicius
10:10 – 10:40	Coffee Break		



10:40 – 13:05	Thin Film Growth- Wurtzites		
10:40 – 11:05	Ferroelectric aluminum boron nitride thin films prepared on 300 mm silicon wafers	Applied Materials	John Hayden
11:05 – 11:30	Introducing Lam's Pulsus™ PLD - enabling PiezoMEMS applications for today and tomorrow	LAM Research	Arjen Janssens
11:30 – 11:55	Advances and challenges in depositing High Scandium-doped AlScN films for PiezoMEMS applications	SPTS/KLA	Adrian Thomas
11:55 – 12:20	Beyond 30 at.% Sc doping for manufacturing-ready, highly uniform, stress neutral Al _{1-x} Sc _x N layers on 8-inch wafers	EVATEC	Dino Faralli
12:20 – 12:45	High-Rate deposition of piezoelectric AlScN films in nanometer to several micrometer range for use in Energy Harvesting and tunable optics	Fraunhofer FEP	Stephan Barth
12:45 – 13:05	Ferroelectric and piezoelectric properties of Ce-Mn substituted ZnO thin films	Kobe University	Isaku Kanno
13:05 – 14:30	Lunch		
14:30 – 15:30	Characterization & Analysis		
14:30 – 15:00	Accelerating the path to reliable piezoelectric thin films with the help of defect characterization	BOSCH	Kuan-Ting Ho
15:00 – 15:30	Reliability of piezoelectric films for MEMS	Penn State	Susan Trolier-McKinstry
15:30 – 17:00	Coffee Break & Poster		
17:30	Transfer to Dinner		
18:00	Conference Dinner	Zinkhütter Hof, Stolberg	



PiezoMEMS 2024, Day 2 - March 20th

Time	Topic	Company / Organisation	Speaker
08:00 – 10:05	Foundries & RTO		
08:00 – 08:25	From Concept to Reality: Addressing Challenges in Piezoelectric MEMS	Silicon Austria Labs	Mohssen Moridi
08:25 – 08:50	PiezoMOEMS: A playground for light manipulation	Sintef	Runar Dahl-Hansen
08:50 – 09:15	Piezoelectric micromachined ultrasonic transducers for imaging and sensing applications	Roma Tre University	Alessandro Stuart Savoia
09:15 – 09:40	Accelerating the industrialization of piezoelectric MEMS technology	ST Micro	Laura Castoldi
09:40 – 10:05	AlScN for high power MEMS actuators	Fraunhofer ISIT	Simon Fichter
10:05 – 10:30	Coffee Break		
10:30 – 12:50	PiezoMEMS Devices, PZT		
10:30 – 10:55	tbd	SAE magnetics	Michael Wong
10:55 – 11:20	poLight [®] piezo MOEMS TLens [®] product architecture and future opportunities	polight	Pierre Craen
11:20 – 11:45	A high-frequency 2D bi-resonant MEMS μ -mirror with large optical FoV	TDK Electronics	Matthias Wulf



11:45 – 12:10	The latest updates in SPP PZT thin film development	Sumitomo Precision	Mario Kiuchi
12:10 – 12:35	Epson's MEMS technology: PrecisionCore --Development strategy and future plan--	Seiko Epson Corporation	Harunobu Koike
12:35 – 12:50	Implementation of edge AI computing functions on piezoelectric MEMS sensors	OMU	Takeshi Yoshimura
12:50 – 14:15	Lunch		
14:15 – 16:10	PiezoMEMS Devices, Al_{1-x}Sc_xN		
14:15 – 14:40	AlScN for Microacoustic Filters	Qualcomm	Thomas Metzger
14:40 – 15:05	Development of piezoelectrically driven MEMS mirrors	Fraunhofer ISIT	Shanshan Gu-Stoppel
15:05 – 15:30	AlScN RF microacoustic resonators and filters for future 5G and 6G cellular radios	Northeastern University	Matteo Rinaldi
15:30 – 15:55	Thin film ScAlN for RF acoustic resonators and filters	IME A-STAR	Liu Chen
15:55 – 16:10	Investigation of AlN thin film deposition into folded membrane MEMS structures	BOSCH	Daniel Pantel
16:10 – 16:40	Closing Remarks		Stephan Tiedke, Susan Trolier-McKinstry